

$\alpha$  is a time of loading a wafer to or unloading the wafer to the robot in Step  $i$ ;

$\mu$  is a time of the robot moving from one wafer-processing step to another;

$\alpha_0$  is a time of the robot unloading a wafer from the loadlocks and aligning the same;

$M_{cd}$  denotes a  $d^{th}$  state during the close-down process of the cluster tool; and

$M_{ce}$  denotes a final state during the close-down process of the cluster tool.

2. The method of claim 1, further comprising a step of determining, by a processor, whether the cluster tool is schedulable at steady state.

3. The method of claim 1, further comprising a step of determining, by a processor, the cluster tool to be schedulable at steady state if  $\vartheta_{max} \leq \vartheta_{iU}$  and  $\psi_1 \leq \vartheta_{iU}$ ,  $i \in N_n$ , where  $\vartheta_{max} = \max\{\vartheta_{iL}, i \in N_n\}$  and  $\psi_1 = 2(n+1)\mu + (2n+1)\alpha + \alpha_0$ .

4. The method of claim 1, wherein the robot waiting time is determined based on a petri net model.

5. A computer-implemented method for scheduling a cluster tool for a close-down process, the cluster tool comprising a single-arm robot for wafer handling, loadlocks for wafer cassette loading and unloading, and  $n$  process modules each for performing a wafer-processing step with a wafer residency time constraint where the  $i$ th process module,  $i \in \{1, 2, \dots, n\}$ , is used for performing Step  $i$  of the  $n$  wafer-processing steps for each wafer, the method comprising:

determining, by a processor, a lower workload  $\vartheta_{iL}$  of Step  $i$  as follows:

$$\vartheta_{iL} = a_i + 4\alpha + 3\mu, \quad i \in N_n \setminus \{1\};$$

$$\vartheta_{iL} = a_1 + 3\alpha + \alpha_0 + 3\mu;$$

determining, by a processor, an upper workload  $\vartheta_{iU}$  of Step  $i$  as follows:

$$\vartheta_{iU} = a_i + 4\alpha + 3\mu + \delta_i, \quad i \in N_n \setminus \{1\};$$

$$\vartheta_{iU} = a_1 + 3\alpha + \alpha_0 + 3\mu + \delta_1;$$

determining, by a processor, that the workloads are unbalanced among the Steps if  $[\vartheta_{iL}, \vartheta_{iU}] \cap [\vartheta_{jL}, \vartheta_{jU}] \cap \dots \cap [\vartheta_{nL}, \vartheta_{nU}] \neq \emptyset$ ; determining, by a processor, a robot waiting time  $\omega_i^d$ ,  $d \leq i \leq n$ ,  $0 \leq d \leq n$  as follows:

1)  $\omega_i^d = \omega_i$ ,  $d \leq i \leq n-1$ ,  $0 \leq d \leq n-1$  where  $\omega_i$  is an  $i^{th}$  robot waiting time at steady state, and obtained by:

$$\omega_{i-1} = \begin{cases} 0, & i \in F \\ \vartheta_{max} - (a_1 + \delta_1 + 3\alpha + \alpha_0 + 3\mu), & 1 \in E \\ \vartheta_{max} - (a_i + \delta_i + 4\alpha + 3\mu), & i \in E \cap \{2, 3, 4, \dots, n\} \end{cases}$$

2)  $\omega_n^0 = \omega_n$ ;

$$3) \omega_n^d = \vartheta_{max} - \psi_{c(d-1)} - \sum_{i=d-1}^{n-1} \omega_i^{d-1},$$

$1 \leq d \leq n-1$ , where  $\psi_{c(d-1)} = 2(n-d+2)\mu + 2(n-d+2)\alpha$ ,  $2 \leq d \leq n$ ; and

4)  $\omega_n^n = a_n$ .

determining, by a processor, a schedule for the close-down process based on the robot waiting time determined;

$a_i$ ,  $i \in N_n$ , is a time that a wafer is processed in the  $i$ th process module;

$\delta_i$  is the wafer residency time constraint of Step  $i$ , given by a pre-determined longest time for which a wafer in the  $i$ th process module is allowed to stay therein after this wafer is processed;

$\alpha$  is a time of loading a wafer to or unloading the wafer to the robot in Step  $i$ ;

$\mu$  is a time of the robot moving from one wafer-processing step to another;

$\alpha_0$  is a time of the robot unloading a wafer from the loadlock and aligning the same;

$\omega_i^d$ ,  $d \leq i \leq n$ ,  $0 \leq d \leq n-1$ , is the robot waiting time in places  $q_i$  during evolutions from  $M_{cd}$  to  $M_{c(d+1)}$ , where  $M_{cd}$  denotes a  $d^{th}$  state during the close-down process of the cluster tool;

$E$  is  $\{i | i \in N_n, \vartheta_{iU} < \vartheta_{max}\}$ , where  $\vartheta_{max} = \max\{\vartheta_{iL}, i \in N_n\}$ ;

$F$  is  $N_n \setminus E$ .

6. The method of claim 5, further comprising a step of determining, by a processor, whether the cluster tool is schedulable at steady state.

7. The method of claim 5, further comprising a step of determining, by a processor, the cluster tool to be schedulable at steady state if  $\vartheta_{iU} < \vartheta_{max}$  with  $i \in E \neq \emptyset$ ,  $\vartheta_{iU} \geq \vartheta_{max}$  with  $i \in F$ , and  $\sum_{i \in E} \omega_{i-1} + \psi_1 \leq \vartheta_{max}$ , and a robot waiting time at steady state is set to make the cluster tool to be schedulable.

8. The method of claim 5, wherein the robot waiting time is determined based on a linear programming model.

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